

WHAT IS CLAIMED IS:

1. A dielectric film structure having a substrate and a dielectric film provided on said substrate, wherein

5 said dielectric film has (001) face orientation
with respect to said substrate; and

a value u in the following equation (1) regarding said dielectric film is a real number greater than 2:

$$10 \quad u = (C_c/C_a) \times (W_a/W_c) \quad \dots \quad (1)$$

where, C_c is a count number of a peak of a $(00l')$ face of said dielectric film in an Out-of-plane X ray diffraction measurement (here, l' is a natural number selected so that C_c becomes maximum); C_a is a count

15 number of a peak of a (h'00) face of said dielectric
film in an In-plane X ray diffraction measurement

(here, h' is a natural number selected so that $C_{h'}$

becomes maximum); W_c is a half-value width of a peak of the (001') face of said dielectric film in an Out

20 of-plane rocking curve X ray diffraction measurement; and W_a is a half-value width of a peak of the $(h'00)$ face of said dielectric film in an In-plane rocking curve X ray diffraction measurement.

25 2. A dielectric film structure according to
claim 1, wherein, in said dielectric film, a count
number of faces other than a (001) face is smaller

than 10% of a count number of the (001') face in the Out-of-plane X ray diffraction measurement and a count number of faces other than a (h00) face is smaller than 10% of a count number of the (h'00) face

5 in the In-plane X ray diffraction measurement (here, h and l are any natural numbers and l' is a natural number selected so that the count number of the peak of the (001') face becomes maximum in the Out-of-plane X ray diffraction measurement and h is a

10 natural number selected so that the count number of the peak of the (h'00) face becomes maximum in the In-plane X ray diffraction measurement).

3. A dielectric film structure according to
15 claim 1, wherein a thickness of said dielectric film is greater than 10 nm and smaller than 20 μ m.

4. A dielectric structure according to claim 1, wherein a crystal structure of said dielectric film
20 is square crystal.

5. A dielectric film structure having a substrate and a dielectric film provided on said substrate, wherein
25 said dielectric film has (111) face orientation with respect to the substrate; and
a value v in the following equation (2)

regarding said dielectric film is a real number greater than 2:

$$v = (C_{111}/C_{-110}) \times (W_{-110}/W_{111}) \quad \dots \quad (2)$$

where, C_{111} is a count number of a peak of a (111) 5 face of said dielectric film in an Out-of-plane X ray diffraction measurement; C_{-110} is a count number of a peak of a (-110) face of said dielectric film in an In-plane X ray diffraction measurement; W_{111} is a half-value width of a peak of the (111) face of said 10 dielectric film in an Out-of-plane rocking curve X ray diffraction measurement; and W_{-110} is a half-value width of a peak of the (-110) face of said dielectric film in an In-plane rocking curve X ray diffraction measurement.

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6. A dielectric film structure according to claim 5, wherein, in said dielectric film, a count number of faces not parallel to the (111) face is smaller than 10% of a count number of the (111) face 20 in the Out-of-plane X ray diffraction measurement and a count number of faces not parallel to the (-110) face is smaller than 10% of a count number of the (-100) face in the In-plane X ray diffraction measurement.

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7. A dielectric structure according to claim 1, wherein a crystal structure of said dielectric film

is rhombic crystal.

8. A dielectric film structure having a substrate and a dielectric film provided on said 5 substrate, wherein:

 said dielectric film has (110) face orientation with respect to said substrate; and
 a value w in the following equation (3) regarding said dielectric film is a real number 10 greater than 2:

$$w = (C_{110}/C_{00m}) \times (W_{00m}/W_{110}) \quad \dots \quad (3)$$

where, C_{110} is a count number of a peak of a (110) face of said dielectric film in an Out-of-plane X ray diffraction measurement; C_{00m} is a count number of a 15 peak of a (00m) face of said dielectric film in an In-plane X ray diffraction measurement (here, m is a natural number selected so that C_{00m} becomes maximum); W_{110} is a half-value width of a peak of the (110) face of said dielectric film in an Out-of-plane rocking 20 curve X ray diffraction measurement; and W_{00m} is a half-value width of a peak of the (00m) face of said dielectric film in an In-plane rocking curve X ray diffraction measurement.

25 9. A dielectric film structure according to claim 8, wherein, in said dielectric film, a count number of faces not parallel to the (110) face is

smaller than 10% of a count number of the (110) face in the Out-of-plane X ray diffraction measurement and a count number of faces not parallel to the (-110) face is smaller than 10% of a count number of the (-5 110) face in the In-plane X ray diffraction measurement.

10. A piezoelectric actuator comprising:
a dielectric film structure according to claim
10 1; and
an electrode for applying voltage to said
dielectric film structure.

11. A piezoelectric actuator comprising:
15 a dielectric film structure according to claim
5; and
an electrode for applying voltage to said
dielectric film structure.

20 12. A piezoelectric actuator comprising:
a dielectric film structure according to claim
8; and
an electrode for applying voltage to said
dielectric film structure.

25 13. An ink jet head comprising:
a piezoelectric actuator including a dielectric

film structure according to claim 1 and an electrode for applying voltage to said dielectric film structure, and wherein said piezoelectric actuator is driven to discharge ink.

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14. An ink jet head comprising:

a piezoelectric actuator including a dielectric film structure according to claim 5 and an electrode for applying voltage to said dielectric film structure, and wherein said piezoelectric actuator is driven to discharge ink.

15. An ink jet head comprising:

a piezoelectric actuator including a dielectric film structure according to claim 8 and an electrode for applying voltage to said dielectric film structure, and wherein said piezoelectric actuator is driven to discharge ink.

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